

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Raaijmakers et al.)	Group Art Unit Unknown
App. No.	:	Unknown)	
Filed	:	January 18, 2001)	
For	:	METHOD OF DEPOSITING SILICON WITH HIGH STEP COVERAGE)	
Examiner	:	Unknown)	

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01/18/01INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

Enclosed is form PTO-1449 listing references, which are not being provided pursuant to 37 CFR §1.98(d), as they were previously either cited by the Office or disclosed in parent application Serial No. 09/264,167, filed March 5, 1999. This Information Disclosure Statement is being filed within three months of the filing date of this application, and no fee is required in accordance with 37 C.F.R. § 1.97(b)(1).

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: January 18, 2001

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